

## Enabling MoS<sub>2</sub> memtransistors via localised helium ion beam irradiation

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Memristors are two-terminal switches which can retain a state of internal electrical resistance based on the history of applied voltage and current. They are the key to neuromorphic hardware and in-memory processing. Recently, resistive switching has been observed over a naturally-occurring grain boundary in MoS<sub>2</sub> monolayers. However, their performance needs to be significantly improved, and viable approaches to incorporate them into the existing silicon technologies are yet to be developed. In this work, we demonstrate a MoS<sub>2</sub>-based memristor via helium ion beam irradiation. The localized ion irradiation introduces site-specific sulphur vacancies in the MoS<sub>2</sub> flake (see Figure 1(a)). The migration of the vacancies under the external electric field induces the resistance switching. We will discuss the viability of further device optimization and large-scale integration.

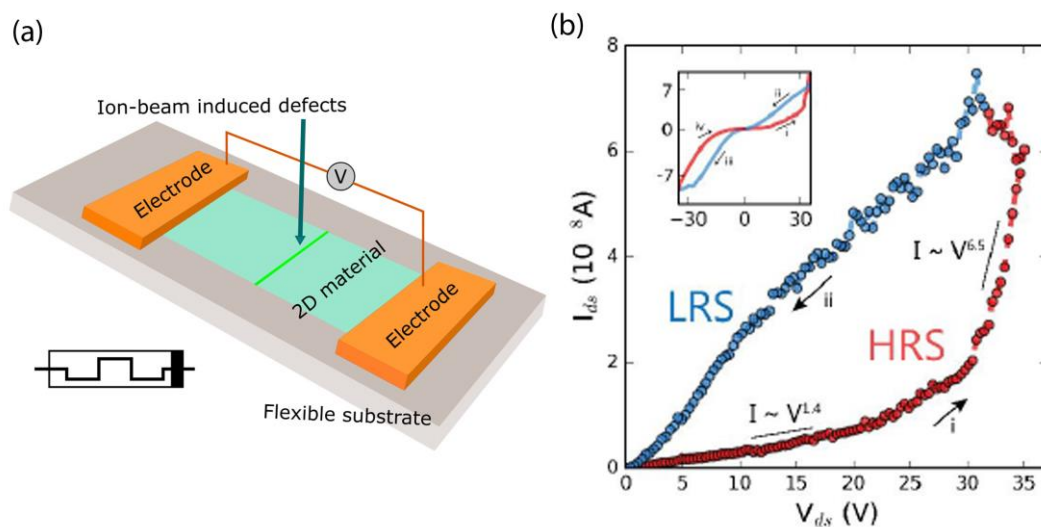


Figure 1 (a) Illustration of the irradiation strategy and the device structure. (b) Positive-bias sweep region of an irradiated monolayer memtransistor device ( $L = 1 \mu\text{m}$ ,  $W = 6 \mu\text{m}$ ) recorded at  $V_g = 0 \text{ V}$ . Inset: full range of the sweep with labelled trace directions. A sharp emergence of non-linearity in the I-V sweep marks the set point from the high resistance state (HRS) to the low resistance state (LRS). The device stays in LRS until a reset bias of negative polarity is reached on the reverse sweep.